

<b>Notice of References Cited</b>	Application/Control No. 10/741,824	Applicant(s)/Patent Under Reexamination CHEN ET AL.	
	Examiner John M. Parker	Art Unit 2823	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	C	US-6,203,613	03-2001	Gates et al.	117/104
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	K	US-			
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	M	US-			

**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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